8.7 GRAZING ANGLE SETUP

Figure 8.25: Time to threshold versus depth for the 200 µm thick non-irradiated Micron (a) and Hamamatsu (b) sensor.

Figure 8.26: Simulation of the time-to-threshold profile of the non-irradiated 200 µm thick n-on-p sensors: (a) operated at 120 V superimposed on data from Micron S23 operated at the same bias voltage. (b) operated at 160 V superimposed on data from Hamamatsu S6 operated at the same bias voltage.